

Attorney Docket: 026281-0306769
Client Reference: OPP 031059 US

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re PATENT APPLICATION of:
CHOI

Confirmation Number: 3859

Application No.: **10/735,912**

Group Art Unit: 1763

Filed: December 16, 2003

Examiner: LUND, Jeffrie Robert

Title: **CHEMICAL VAPOR DEPOSITION APPARATUS AND METHOD**

AMENDMENT UNDER 37 C.F.R. § 1.312

Mail Stop Issue Fee
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Please consider the following amendment and remarks regarding the above-identified allowed application. It is respectfully submitted that the following amendment does not present any new issues of enablement or allowability, and as such should be entered in its entirety. There are no amendments to the claims.